

INFORMATION DISCLOSURE STATEMENT

Case Name.

M. Megens 1-10-5

Serial No. 10

10/040017 M. Megens, et al.

Applicant: Filing Date: Group:

January 4, 2002 1756

**U.S. PATENT DOCUMENTS** 

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date
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**FOREIGN PATENT DOCUMENTS** 

	Document Number	Date	Country	Class	Subclass	Translation
-						

OTHER (including Author, Title, Date, Pertinent Pages, etc.)

al	1	Lee, K.Y., LaBianca, N., Rishton, S.A., Zolghamain, S., Gelorme, J.D., Shaw, J., Chang, T.HP., Micromachining Applications Of A High Resolution Ultrathick Photoresist, J. Vac. Sci. Technol. B 13(6) Nov/Dec 1995, pp. 3012-3016.

<sup>\*\*\*</sup>References listed beyond AZ would list as AA-1, AB-2, AC-3 thru AZ-26.

EXAMINER DATE CONSIDERED 6/29/4/

\*Examiner: Initial/if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant

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<sup>\*\*\*</sup>Note First Page ONLY Header/Footer. Subsequent pages must ONLY have page # layout as header